

12. Akronimi metoda/uređaja/instrumenata

| AKRONIMI | METODE-UREĐAJI-INSTRUMENTI |
|----------------|--|
| 3DAP | 3-dimensional atom probe |
| AAS | Atomic absorption spectroscopy |
| ADES | Angle dispersed electron spectroscopy |
| AED | Auger electron diffraction |
| AEM | Analytical electron microscopy |
| AES | Auger emission (electron) spectrometry; <i>Auger-ova emisijska spektroskopija</i> |
| AEFS | Absorption edge fine structure |
| AETEM | Atomic-resolution environmental transmission electron microscopy |
| AFAM | Atomic-force acoustic microscopy |
| AFM | Atomic force microscopy |
| APFIM | Atomic probe field ion microscopy |
| APS | Appearance potential spectroscopy |
| ARP(ES) | Angle-resolved photoemission (spectroscopy) |
| ATEM | Analytical transmission electron microscopy |
| ATR | Attenuated total reflectance |
| AXRS | Anomalous X-ray scattering |
| BET | BET surface area measurement |
| BiFC | Bimolecular fluorescence complementation |
| BKD | Backscatter Kikuchi diffraction |
| BLE | Bombardment-induced light emission |
| BRET | Bio-luminescence resonance energy transfer |
| BSE | Back scattered electrons |
| BSED | Back scattered electron diffraction |
| CAFM | Conducting atomic force microscopy |
| CAICISS | Coaxial impact collision ion scattering spectroscopy |
| CBD | Convergent beam diffraction |
| CBED | Convergent beam electron diffraction |
| CCM | Charge collection microscopy |
| CDI | Coherent diffraction imaging |
| CEMS | Conversion electron Mössbauer spectroscopy |
| CET | Cryo-electron tomography |
| CFM | Chemical force microscopy |
| CIS | Constant initial state spectroscopy |
| CL | Cathodo-luminescence |
| CLSM | Confocal laser scanning microscopy |
| CMR | Contact microradiography |
| COSY | Correlation spectroscopy |
| CPAA | Charge particle activation analysis |
| Cryo-EM | Cryo-electron microscopy |
| CS-AFM | Current-sensing atomic force microscopy |
| CTEM | Conventional transmission electron microscopy (TEM) |
| CTXM | Conventional scanning X-ray microscopy |
| CV | Cyclic voltametry |
| DAC | Diamond anvil cell |
| DE(T)A | Dielectric thermal analysis |
| dHvA | De Haas-van Alphen effect |
| DIC | Differential interference contrast microscopy |
| DLS | Dynamic light scattering |
| DLTS | Deep level transient spectroscopy |
| DMA | Dynamic mechanical analysis |
| DPC | Differential phase contrast |
| DSC | Differential scanning calorimetry; <i>diferencijalna skenirajuća/pretražna kalorimetrija</i> |

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| DTA | Differential thermal analysis; <i>diferencijalna termička analiza</i> |
| DVS | Dynamic vapor sorption |
| ECD | Electron coincidence spectroscopy |
| EBIC | Electron beam induce conductivity |
| EBS | Electron backscatter diffraction |
| EBSP | Electron backscatter spectroscopy |
| ECOSY | Exclusive correlation spectroscopy |
| ECT | Electrical capacitance tomography |
| ED | Electron diffraction; <i>elektronska difrakcija</i> |
| EDS | Energy dispersive (X-ray) spectrometry |
| EDX | Energy dispersive (X-ray) spectroscopy/analysis |
| EELFS | Electron energy loss fine structure spectrometry |
| EEM | Emission electron microscopy |
| EFM | Electrostatic force microscope |
| EFTEM | Energy-filtering transmission electron microscopy |
| EMMA | Analytical electron microscopy with microanalysis |
| EELS | Electron energy loss spectrometry |
| EID | Electron induced desorption |
| EIT | Electrical impedance tomography |
| ELNES | Near-edge fine structure in EELS |
| ELS | Electropheric light scattering |
| ENDOR | Electron nuclear double resonance |
| EPES | Elastic peak electron spectroscopy |
| EPM(A) | Electron probe microanalysis |
| EPR | Electron paramagnetic resonance spectrometry |
| ERT | Electrical resistivity tomography |
| ESCA | Electron spectroscopy for chemical analysis |
| ESEM | Environmental scanning electron microscopy |
| ESD | Electron stimulated desorption |
| ESD(MS) | Electron stimulated desorption mass spectrometry |
| ESI | Electron spectroscopic imaging |
| ES-MS | Electro spray mass spectrometry |
| ESI-MS | Electro spray ionization mass spectrometry |
| ESR | Electron spin resonance spectroscopy; <i>elektronsko spinska rezonancija</i> |
| ESTM | Electrochemical scanning tunneling microscopy |
| ETEM | Environmental transmission electron microscopy |
| EXAFS | Extended (X-ray) absorption fine structure spectroscopy |
| EXELFS | Extended (electron) energy loss fine structure |
| EXSY | Exchange spectroscopy |
| FAB(MS) | Fast atom bombardment mass spectrometry |
| FCCS | Fluorescence cross-correlation spectroscopy |
| FCS | Fluorescence correlation spectroscopy |
| FE-AES | Field emission Auger electron spectroscopy |
| FEM | Field emission microscopy |
| FESEM | Field emission scanning electron microscopy |
| FFM | Friction force microscope |
| FIB | Focused ion beam microscopy |
| FIM | Field-ion microscope |
| FIM | Field-ion microscope-atom probe |
| FLIM | Fluorescence lifetime imaging |
| FRET | Fluorescence resonance energy transfer |
| FTICR | Fourier transform ion cyclotron resonance |
| FTIR | Fourier transform infrared absorption spectroscopy |
| FT-MS | Fourier-transform mass spectrometry |
| GC-MS | Gas chromatography-mass spectrometry |
| GDMS | Glow discharge mass spectrometry |

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| GDOES | Glow discharge optical spectroscopy |
| GDOS | Glow discharge optical spectrometry |
| GDS | Glow discharge spectroscopy |
| GISAXS | Grazing incidence small-angle X-ray scattering |
| GIXD | Grazing incidence X-ray diffraction |
| GIXR | Grazing incidence X-ray reflectivity |
| GLC | Gas-liquid chromatography |
| GSIMS | Gentle secondary ion mass spectroscopy |
| HAS | Helium atom scattering |
| HPLC | High performance liquid chromatography |
| HP-XPS | High-pressure X-ray photoelectron spectroscopy |
| HREELS | High resolution electron energy loss spectrometry |
| HRSEM | High-resolution scanning electron microscopy |
| HRTEM | High-resolution transmission electron microscopy; <i>visoko razlučujuća transmisijaska elektronska mikroskopija</i> |
| HFCVD | Hot filament chemical vapor deposition |
| HVEM | High voltage electron microscopy |
| IABD | Ion beam assisted spectroscopy |
| IAES | Ion-induced Auger electron spectroscopy |
| IBM | Ion beam mixing |
| IBIC | Ion beam induced charge microscopy |
| ICP-MS | Inductively coupled plasma mass spectrometry |
| ICR | Ion cyclotron resonance |
| IETS | Inelastic electron tunneling spectroscopy |
| IGA | Intelligent gravimetric analysis |
| IIX | Ion induced X-ray analysis |
| IMP(A) | Ion microprobe analysis |
| INS | Ion neutralization spectroscopy (Inelastic neutron scattering) |
| IPE | Inverse photoemission |
| IR(S) | Infrared spectroscopy; <i>infracrvena spektroskopija</i> |
| ISS | Ion scattering spectroscopy |
| ITC | Isothermal titration calorimetry |
| IVEM | Intermediate voltage electron microscopy |
| LAD | Large angle diffraction |
| LALLS | Low-angle laser light scattering |
| LAMMA | Laser microprobe mass analysis |
| LAXS | Low angle X-ray scattering |
| LC-MS | Liquid chromatography-mass spectrometry |
| LEED | Low-energy electron diffraction; <i>difrakcija elektrona niskih energija</i> |
| LEELS | Low-energy electron loss spectrometry; <i>nisko-energijska elektronska gubitna spektroskopija</i> |
| LEEM | Low-energy electron microscopy; <i>nisko-energijska elektronska mikroskopija</i> |
| LEIS | Low energy ion (back) scattering |
| LFM | Lateral force microscopy |
| LIBS | Laser induced breakdown spectroscopy |
| LIMA | Laser induced ion mass analysis |
| LM | Light microscopy |
| LOES | Laser optical emission spectrometry |
| LS | Light (Raman) scattering |
| MALDI | Matrix-assisted laser desorption/ionization |
| MBE | Molecular beam epitaxy |
| MEIS | Medium energy ion scattering |
| MExFM | Magnetic exchange force microscopy |
| MFM | Magnetic force microscope |
| MIT | Magnetic induction tomography |
| MOCVD | Metal organic chemical vapor deposition |

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| MOLE | Molecular optical laser examiner |
| MPCVD | Microwave plasma assisted chemical vapor deposition |
| MRFM | Magnetic resonance force microscopy |
| MRI | Magnetic resonance imaging |
| MS | Mass spectroscopy |
| MS | Mössbauer Spectroscopy; <i>Mössbauerova spektroskopija</i> |
| MS/MS | Tandem mass spectrometry |
| MTA | Micro-thermal analysis |
| NAA | Neutron activation analysis |
| ND | Neutron diffraction; <i>neutronska difrakcija</i> |
| NDP | Neutron depth profiling |
| NDT | Non-destructive testing |
| NEXAFS | Near-edge X-ray absorption fine structure |
| NIS | Neutron inelastic scattering |
| NLOS | Nonlinear optical spectroscopy; <i>nelinearna optička spektroskopija</i> |
| NMR | Nuclear Magnetic Resonance (Spectroscopy); <i>nuklearna magnetska rezonancija</i> |
| NOESY | Nuclear Overhauser effect spectrometry |
| NQR | Nuclear quadruple Resonance |
| NSOM | Near-field scanning optical microscopy |
| OES | Optical emission spectrometry |
| OIM | Orientation imaging microscopy |
| OM | Optical microscopy |
| PACT | Photoacoustic computed tomography |
| PAM | Photoacoustic microscopy |
| PAS | Positron-annihilation spectrometry |
| PALS | Positron annihilation lifetime spectroscopy |
| PACT | Photoacoustic computed tomography |
| PAT | Photoacoustic tomography |
| PAX | Photoemission of adsorbed xenon |
| PAS | Positron annihilation spectrometry |
| PC(S) | Photocurrent spectroscopy |
| PD | Photodesorption |
| PECVD | Plasma enhanced chemical vapor deposition |
| PED | Photoelectron diffraction |
| PEEM | photoemission electron microscopy |
| PESM | Photoelectron spectro microscopy |
| PEYS | Photoelectron spectroscopy |
| PFM | Photonic force microscopy |
| PIXE | Particle (proton) induced X-ray emission |
| PLD | Pulse laser deposition |
| PM-IRAS | Polarization modulated infrared reflection absorption spectroscopy |
| PSD(MS) | Photon-stimulated desorption mass spectroscopy |
| PTMS | Photo-thermal micro-spectrometry |
| PVD | Physical vapor deposition |
| QENS | Quasi-elastic neutron scattering |
| RAIRS | reflection absorption infrared spectroscopy |
| RAXRS | Resonant anomalous X-ray scattering |
| RBS | Rutherford backscattering spectroscopy; <i>Rutherfordovo odzivno raspršenje</i> |
| RDE | Reactive deposition epitaxy |
| RED | Reflection electron diffraction |
| REEL | Reflection electron energy-loss |
| REELS | Reflection electron energy-loss spectrometry |
| REFLEXAFS | Reflected extended X-ray absorption fine-structure spectroscopy |
| REM | Reflection electron microscopy |
| RHEED | Reflection high-energy electron diffraction; <i>visokoenergijska refleksijska elektronska difrakcija</i> |

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| RIS | Rydberg ionization spectroscopy |
| RRS | Resonance Raman spectrometry |
| RS | Raman spectroscopy; <i>Ramanova spektroskopija</i> |
| SAM | Scanning Auger microscopy |
| SAM | Scanning acoustic microscopy |
| SANS | Small angle neutron scattering |
| SAXS | Small-angle X-ray scattering; <i>rentgenska difrakcija/raspršenje pod malim kutom</i> |
| SAXRD | Small-angle X-ray diffraction |
| SCANIIR | Surface composition by analysis of neutral species and ion-impact radiation |
| SCM | Scanning capacitance microscopy |
| SD | Sputter deposition |
| SE | Spectrometric ellipsometry |
| SEAM | Scanning electro acoustic microscopy |
| SEC | Size exclusion chromatography |
| SEM | Scanning electron microscopy; <i>rasterski/pretražni/skenirajući elektronski mikroskop</i> |
| SEIRA | Surface enhanced infrared absorption spectrometry |
| SERS | Surface enhanced Raman spectrometry/spectroscopy |
| SEXAFS | Surface extended x-ray absorption fine structure spectroscopy (Surface EXAFS) |
| SFA | Surface force apparatus |
| SICM | Scanning ion-conduction microscopy |
| SHEED | Scanning high energy electron diffraction |
| SICM | Scanning ion conductance microscopy |
| SIIMS | Secondary ion imaging mass spectrometry |
| SIMS | Secondary ion mass spectrometry; <i>masena spektroskopija sekundarnih iona</i> |
| SIPS | Sputter-induced photon spectroscopy |
| SLAM | Scanning laser acoustic microscopy |
| SNMS | Secondary neutral mass spectrometry |
| SNOM | Scanning near-field optical microscopy |
| SOM | Scanning optical microscopy |
| SOMSEM | SOM in SEM |
| SPAM | Scanning photo acoustic microscopy |
| SPECT | Single photon emission computed tomography |
| SPM | Scanning probe microscopy |
| SPR | Surface plasmon resonance |
| SP-STM | Spin-polarized scanning-tunneling microscope/microscopy |
| SQUID | Superconducting quantum interference device |
| SRM-CE/MS | Selected-reaction-monitoring capillary-electrophoresis mass-spectrometry |
| SSNMR | Solid-state nuclear magnetic resonance |
| STEM | Scanning transmission electron microscopy |
| STM | Scanning tunneling microscope; <i>rasterski/pretražni tunelirajući mikroskop</i> |
| STXM | Scanning transmission X-ray microscopy |
| SXE | Soft X-ray emission |
| SXM | Scanning X-ray microscopy |
| TAT | Thermo-acoustic tomography |
| TACT | Thermo-acoustic computed tomography |
| TDP | Temperature programmed desorption |
| TEM | Transmission electron microscopy; <i>Transmisijska elektronska mikroskopija</i> |
| TFM | Thermic force microscope |
| TEM-EPMA | Transmission electron microscopy with electron probe microanalysis |
| THEED | Transmission high energy electron diffraction |
| TG(A) | Thermogravimetry (analysis); <i>termogravimetrija</i> |
| TIRFM | Total internal reflection fluorescence microscopy |
| TL | Termoluminescence |
| TMA | Thermo-mechanical analysis |
| TOF-SIMS | Time of flight secondary ion mass spectrometry |
| TRXRD | Time resolved X-ray diffraction |

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| TXRF | Total X-ray reflection fluorescence spectroscopy (analysis) |
| UHRTEM | Ultra high-resolution transmission electron microscopy |
| UHVCVD | Ultra high vacuum chemical vapor deposition |
| UPS | Ultraviolet photoelectron/photoemission spectroscopy |
| VEDIC | Video-enhanced differential interference contrast microscopy |
| μPS | Muon-precession spectrometry |
| XAES | X-ray induced Auger electron spectrometry |
| XAFS | X-ray absorption fine structure spectroscopy |
| XANES | X-ray absorption near edge structure |
| XAS | X-ray absorption spectrometry |
| X-CTR | X-ray crystal truncation rod scattering |
| XDS | X-ray diffuse scattering |
| XPEEM | X-ray photoelectron emission microscopy |
| XPS | X-ray photoelectron/photoemission spectroscopy |
| XR | X-ray reflectivity |
| XRD | X-ray diffraction; <i>rentgenska difrakcija</i> |
| XRF | X-ray fluorescence (analysis); <i>rentgenska fluorescencija</i> |
| XRM | X-ray microscopy |
| XSW | X-ray standing wave technique |
| WAXS | Wide angle X-ray scattering |
| WDS (WDXEF) | Wavelength-dispersive spectrometry |

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| AC | Alternating current |
| APPJ | Atmospheric pressure plasma jet |
| ATR | Attenuated total reflectance |
| BEN | Bias enhanced nucleation |
| BGA | Bulk glassy alloy |
| BMG | Bulk metallic glass |
| CEOS | Image C _s corrector (u elektronskom mikroskopu za poboljšanje razlučivanja) |
| CMOS | Complementary metal oxide semiconductor |
| CPMAR | Cross polarization magic angle rotation |
| CET | Capacitance equivalent thickness |
| CLIC | Compact linear collider |
| CPMAS | Cross polarization magic angle spinning |
| DAC | Diamond anvil cell |
| DC | Direct current |
| DFT | Density functional theory |
| DLC | Diamond like carbon |
| DSMC | Direct simulation Monte Carlo |
| DWCNT | Double-wall carbon nanotube |
| ECAP | Equal channel angular pressing |
| ECP | Electron channeling pattern |
| ED | Electro-deposition |
| EDC | Energy distribution curve |
| EFE | Electron field emission |
| ELPEC | Electrode less PEC |
| EPES | Elastic peak electron spectra |
| ERDA | Elastic recoil detection analysis |
| FEED | Field emission energy distributions |
| FEG | Field emission gun |
| FET | Field effect transistor |
| FIB | Focused ion beam |
| FFT | Fast Fourier transformation |
| GFA | Glass-forming ability |
| GIF | Gatan image filter |

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| GMR | Giant magnetoresistance |
| HAADF | High-angle annular dark field |
| HCD | Hollow cathode discharge |
| HEMTs | high electron mobility transistors |
| HOLZ | Higher order Laue zone |
| HPT | High pressure torsion |
| IBM | Ion beam mixing |
| IMFP | Inelastic mean free path |
| IGC | Inert gas condensation |
| ITO | Indium-tin oxide |
| LED | Light-emitting diode |
| LHC | Large hadron collider |
| MA | Mechanical alloying |
| MEMS | Micro-electron mechanical devices |
| MG | Mechanical grinding |
| MM | Mechanical milling |
| (M)NRs | M je oznaka za neki element, primjerice: SiNRs –Silicon nanorods; CNRs - Carbon nanorods |
| MRAM | Magnetoresistive random access memory |
| MWCNT | Multi-wall carbon nanotube |
| NCD | Nanocrystalline diamond |
| NEG | Non-evaporable getter |
| NIM | Negative-index material |
| NLOP | Non-linear optical property |
| NSLS | National synchrotron light source (Brookhaven National Laboratory) |
| PA | Polyamide |
| PBG | Photonic band gap |
| PEC | Photo-electrochemical |
| PET | Polyethylene terephthalate |
| PMMA | Polymethyl methacrylate |
| PS | Polystyrene |
| RDE | Reactive deposition epitaxy |
| RDF | Radial distribution function |
| RSM | Response surface methodology |
| SACP | Selected area channeling pattern |
| SAD | Selected area diffraction |
| SAED | Selected area electron diffraction |
| SAW | Surface acoustic wave |
| SDP | Severe plastic deformation |
| SE | Secondary electron |
| SES | Secondary electron emission |
| SEP | Surface excitation (material) parameter |
| SFG | Sum frequency generation |
| SPD | Severe plastic deformation |
| SSAR | Solid-state amorphization |
| SWCNT | Single-wall carbon nanotubes |
| TCO | Transparent conducting oxides |
| TCP | Transmission channeling pattern |
| TCR (TCRF) | Temperature coefficients of resistance |
| TFS | Thin film system |
| TOF | Time of flight |
| UHV | Ultrahigh vacuum |
| XMCD | X-ray magnetic circular dichroism |
| WCA | Water contact angle |
| WF | Work function |
| ZAF | Atomic number, absorption and fluorescence correction pattern |